



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Thomas McWaid et al.
Title: System For Sensing A Sample
Application No.: 10/729,609 Filing Date: December 5, 2003
Examiner: Not yet assigned Group Art Unit: 2856
Docket No.: TNCR.169US2 Conf. No.: 2888

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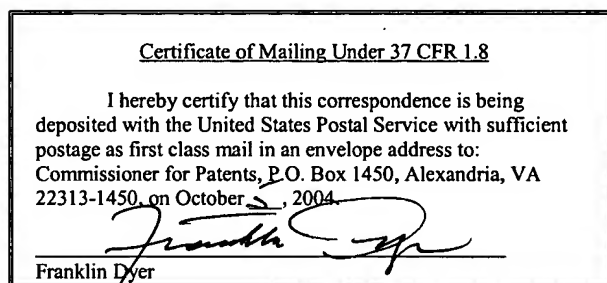
INFORMATION DISCLOSURE STATEMENT

Dear Sir:

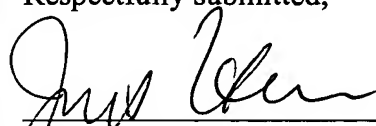
Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application. Copies of the documents listed on the accompanying Form PTO-1449 were previously submitted in Application No. 09/313,962, filed May 18, 1999, now U.S. Patent No. 6,520,505, Application No. 08/730,641, now U.S. Patent No. 5,948,972, issued September 7, 1999, and Application No. 08/362,818, filed December 22, 1994, now U.S. Patent No. 5,705,741, issued January 6, 1998, from which this Application claims an earlier effective filing date.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

This information disclosure statement is submitted under 37 C.F.R. § 1.97(c). A check including \$180.00 for the information disclosure statement fee under 37 C.F.R. § 1.17(p), is enclosed. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

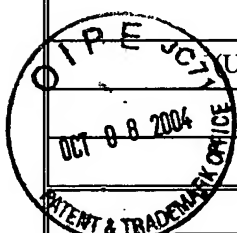


Respectfully submitted,


James S. Hsue
Reg. No. 29,545

10/5/04
Date

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	Thomas McWaid	2888
	Filing Date	Group
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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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	2	2,728,222	Dec., 1955	Becker et al.			
	3	3,283,568	Nov., 1966	Reason.			
	4	4,103,542	Aug., 1978	Wheeler et al.			
	5	4,391,044	Jul., 1983	Wheeler.			
	6	4,441,177	Apr., 1984	Groh et al.			
	7	4,574,625	Mar., 1986	Olasz et al.			
	8	4,641,773	Feb., 1987	Morino et al.			
	9	4,669,300	Jun., 1987	Hall et al.			
	10	4,724,318	Feb., 1988	Binnig.			
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	43	2249910	Oct., 1990	JP				
	44	2009409	Jun., 1979	GB				
	45	WO 88/04047	Jun., 1988	WO.				
	46	WO 94/08204	Apr., 1994	WO				
	47	WO 94/25888	Nov., 1994	WO.				
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60	"Two-Scanning Tunneling Microscope Devices for Large Samples," G.B. Picotto et al., Review of Scientific Instruments, vol. 64, No. 9, Sep. 1993, pp. 2699-2701.
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	63	"Long Range Constant Force Profiling for Measurement of Engineering Surfaces," L.P. Howard, Review of Scientific Instruments, vol. 63, No. 10, Oct. 1992, pp. 4289-4295.	
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	67	"The National Institute of Standards and Technology Molecular Measuring Machine: A Long-Range Scanning Tunneling Microscope for Dimensional Metrology," E.C. Teague, Microbeam Analysis, 1989, pp. 545-547.	
	68	"Products for Micropositioning," Product Information Brochure published by Physik Instrumente (PI) GmbH & Co., no date available.	
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	70	"Series 88 Fiber-Optic Displacement Sensors," G. J. Philips, Sensors, Feb. 1995.	
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78	"A rocking beam electrostatic balance for the measurement of small forces," G. L. Miller et al., Rev. Sci. Instrum., vol. 62, No. 3, Mar. 1991, pp. 705-709.
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80	Written Opinion dated March 29, 2001
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